

10/523976

DT05 Rec'd PCT/PTO 08 FEB 2005

Docket No.: ISH-0227
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Toshihiro Tsuchiya

Application No.: NEW APPLICATION

Confirmation No.: N/A

Filed: February 8, 2005

Art Unit: N/A

For: WAFER POLISHING METHOD AND
APPARATUS

Examiner: Not Yet Assigned

FIRST PRELIMINARY AMENDMENT

MS PCT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

INTRODUCTORY COMMENTS

Prior to examination on the merits, please amend the above-identified U.S. patent application as follows:

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks/Arguments begin on page 5 of this paper.